

of separately defined areas arranged a matrix defined by ~~[in]~~ columns and rows ~~[in a matrix]~~.

Claim 9. (currently amended) The system of claim ~~[5]~~ 8 in which the relationship of the number ~~(N)~~ of separately defined areas in the rows to the number of separately defined areas ~~[(N)]~~ in the columns is $\text{rows}_N = \text{columns}_N$.

Claim 10. (currently amended) The system of claim ~~[6]~~ 8 in which the relationship of the number ~~(N)~~ of separately defined areas in one column to ~~[of]~~ the number of separately defined areas in an adjacent column is $\text{areas in column}_N = N$ and areas in adjacent column ~~[N+1]~~ $N+1 = N+1$.

Claim 11. (currently amended) The system of claim ~~[6]~~ 8 in which the relationship of the number ~~(N)~~ of separately defined areas in one row to of the number of separately defined areas in an adjacent row is $\text{areas in row}_N = N$ and areas in adjacent row ~~[N+1]~~ $N+1 = N+1$.

Claim 12. (currently amended) The system of claim 1 in which the plasma sources are controlled such that the materials originating from the sources are deposited ~~[[on-an]]~~ upon an area of the substrate in at least one of 1) a sequential layer ~~[[by-layer]]~~ deposition and 2) a co-deposition ~~[[relationship]]~~.

AMENDMENT AND RESPONSE TO THE OFFICE COMMUNICATION MAILED ON FEBRUARY 23, 2007
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Claim 13. (currently amended) ~~[A substrate holder for the]~~ The system of claim 8
~~[1 comprising]~~ wherein the substrate comprises a side surface of a block positioned
within the central location of the chamber, the block having a multiplicity of
~~[longitudinally extending]~~ cylindrical substrate elements extending from the side
surface thereof, each cylindrical substrate element individually defining a selected
area, [substrates] the cylindrical substrate elements maintained in an array of
cylindrical columns and cylindrical rows formed within [in] the block, in which [an] the
upper surfaces of the cylindrical substrate elements comprise the discrete areas [is]
exposed to [the ions directed from] the sources.

Claim 14. (currently amended) The system [holder] of claim [11] 13 in which the
cylindrical substrate elements are [upper surface of the substrate is] inset within the
block in a matrix and a plate having a matrix of openings concentric with the matrix of
elements in the block is applied facing the surface of the block, such that the
openings in the plate are aligned with the elements and the cross-section area of an
opening in the plate [upper surface of the column in the block in which the substrate
is positioned is less than the [transverse] cross-section area of the [upper] surface of
the corresponding concentric cylindrical [substrate] element [exposed to the ions
directed from the sources].

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